Ryutaro Maeda

List of Publications by Year
in descending order

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37	365	840776 11	794594 19
papers	citations	h-index	g-index

37	37	37	255
all docs	docs citations	times ranked	citing authors

#	Article	IF	Citations
1	Mode localization analysis and characterization in a 5-beam array of coupled nearly identical micromechanical resonators for ultra-sensitive mass detection and analyte identification. Microsystem Technologies, 2012, 18, 1923-1929.	2.0	39
2	Flexible Implantable Microtemperature Sensor Fabricated on Polymer Capillary by Programmable UV Lithography With Multilayer Alignment for Biomedical Applications. Journal of Microelectromechanical Systems, 2014, 23, 21-29.	2.5	33
3	A mass multi-warning scheme based on one-to-three internal resonance. Mechanical Systems and Signal Processing, 2020, 142, 106784.	8.0	31
4	Passive piezoelectric single-side MEMS DC current sensor with five parallel PZT plates applicable to two-wire DC electric appliances without using cord separator. Microsystem Technologies, 2013, 19, 923-927.	2.0	29
5	Developing integrated piezoelectric direct current sensor with actuating and sensing elements. Micro and Nano Letters, 2013, 8, 858-860.	1.3	25
6	Toward the World Smallest Wireless Sensor Nodes With Ultralow Power Consumption. IEEE Sensors Journal, 2014, 14, 2035-2041.	4.7	25
7	Analytical study on cantilever resonance type magnet-integrated sensor device for micro-magnetic field detection. Microsystem Technologies, 2015, 21, 1167-1172.	2.0	20
8	Internal Resonance Phenomena in Coupled Ductile Cantilevers With Triple Frequency Ratioâ€“Part I: Experimental Observations. IEEE Sensors Journal, 2019, 19, 5475-5483.	4.7	20
9	Multiplication in Frequencies by Synchronized and Superharmonic Oscillations: Sensing Verification With Picogram Order Microspheres. IEEE Sensors Journal, 2015, 15, 4464-4471.	4.7	19
10	Internal Resonance Phenomena in Coupled Ductile Cantilevers With Triple Frequency Ratio-Part II: A Mass Sensitivity Amplification Schemes. IEEE Sensors Journal, 2019, 19, 5484-5492.	4.7	18
11	Synchronous identification and successive detection of multiple traces with tunable coupling oscillators. Mechanical Systems and Signal Processing, 2022, 166, 108395.	8.0	15
12	Analytical study on effect of ring geometry on frequency shift of piezoelectric ring-shaped resonator. Microsystem Technologies, 2012, 18, 773-778.	2.0	9
13	Analytical studies on amplitude change enhancement in coupled aluminium nitride coated single crystal silicon oscillator pair applicable to ultraâ€sensitive resonating microfluidic flowmeters. Micro and Nano Letters, 2013, 8, 609-613.	1.3	9
14	An analytical study of the effect of a support geometry on frequency shift and support loss of piezoelectric ring-shaped resonators for healthcare and environmental applications. Microsystem Technologies, 2013, 19, 503-508.	2.0	8
15	Development of Implantable Wireless Sensor Nodes for Animal Husbandry and MedTech Innovation. Sensors, 2018, 18, 979.	3.8	8
16	Noninvasive Passive Measurement of Multiphase Currents in IoT. IEEE Transactions on Industrial Electronics, 2021, 68, 12860-12870.	7.9	7
17	Autoparametric Internal Resonance in Coupled Oscillator: An Excitation Amplitude Insensitive Mass Sensing Scheme With a Roof Tilting. IEEE Sensors Journal, 2022, 22, 1998-2005.	4.7	7
18	Flexible integration of MEMS and IC for low-cost production of wireless sensor nodes. Microsystem Technologies, 2013, 19, 775-781.	2.0	6

#	Article	IF	Citations
19	A Low 1/f Noise Tunnel Magnetoresistance Accelerometer. IEEE Transactions on Instrumentation and Measurement, 2022, 71, 1-11.	4.7	6
20	Frontside-micromachined planar piezoresistive vibration sensor: Evaluating performance in the low frequency test range. AIP Advances, 2014, 4, 017112.	1.3	5
21	A Detection Error Correction Scheme Aiming at Gradient Nonlinear Problem in Cantilever-Based Sensors. IEEE Sensors Journal, 2019, 19, 11797-11804.	4.7	5
22	Fabrication and evaluation of aluminum nitride based MEMS piezoelectric vibration sensors for large-amplitude vibration applications. Microsystem Technologies, 2021, 27, 235-242.	2.0	5
23	Chip to wafer temporary bonding with self-alignment by patterned FDTS layer for size-free MEMS integration. , 2011, , .		4
24	Liftâ€•off process of piezoelectric leadâ€“zirconateâ€“titanate thin film using selfâ€assembled monolayer as sacrificial layer. Micro and Nano Letters, 2013, 8, 138-142.	1.3	4
25	Selective Cu Patterning on Polyimide Using UV Surface Treatment and Electroless Plating. Journal of Photopolymer Science and Technology = [Fotoporima Konwakai Shi], 2015, 28, 157-161.	0.3	3
26	Cavityâ€first approach for microelectromechanical systemâ€“CMOS monolithic integration. Micro and Nano Letters, 2013, 8, 700-703.	1.3	2
27	High-efficient Chip to Wafer Self-alignment and Bonding for Flexible and Size-free MEMS-IC Integration. IEEJ Transactions on Sensors and Micromachines, 2012, 132, 230-234.	0.1	2
28	PZT Film Formation with Use of Spray Coating Method. IEEJ Transactions on Sensors and Micromachines, 2003, 123, 588-589.	0.1	1
29	A Measurement Method for the Power Generation Characteristics of Piezoelectric Elements. IEEJ Transactions on Sensors and Micromachines, 2004, 124, 30-31.	0.1	0
30	High-efficient and high-accurate chip to wafer bonding for size-free MEMS-IC integration by using fine patterned self-assembled monolayer. , 2012, , .		0
31	Subâ€Micronâ€Wide Surficial Trench Frames to Define the Coating Areas of Sensitive Layers on Silicon <scp>MEMS</scp> Resonant Chemical Sensors. Electronics and Communications in Japan, 2013, 96, 60-66.	0.5	0
32	Self-alignment observation and conductivity evaluation in micro chips integration with square binding pattern. Microsystem Technologies, 2015, 21, 1203-1208.	2.0	0
33	Large-scale Experiment of Power Consumption Monitoring Using Wireless Sensor Nodes. Transactions of the Society of Instrument and Control Engineers, 2016, 52, 698-706.	0.2	0
34	Guest Editorial Special Issue on Selected Papers From the IEEE SENSORS 2015 Conference. IEEE Sensors Journal, 2016, 16, 8671-8671.	4.7	0
35	Developing MEMS Electric Current Sensors for End-use Monitoring of Power Supply: Part X â€" An IEEE802.11g Protocol Compliant Integratable Dual-frequency Coaxial Microstrip Antenna. , 2021, , .		0
36	Developing MEMS Electric Current Sensors for End-use Monitoring of Power Supply: Part XI - A Nonlinear Error Correction Scheme. , 2021, , .		0

#	Article	IF	Citations
37	Wireless Sensor Nodes with Ultra-low Power Consumption for Low-Frequency Vibration Monitoring. IEEJ Transactions on Sensors and Micromachines, 2015, 135, 355-360.	0.1	0